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MULTI-CELL BATERY MONITOR ASIC BY DESNO FOR TOYOTA PRIUS ZVW51 - DETAILED STRUCTURE ANALYSIS REPORT

June, 2016. This sixty-four page document is one of six reports, each analyzing various segments of the ZVW51 system. This report is focusing on Multi-cell battery monitor ASIC and its detailed structure analysis. Three dies are stacked in one package. The upper die is not connected eclectically. We estimate that the function of the middle die is daisy chain communication, voltage reference and biasing, while the lower die is a multiplexer (MUX) and Analog to digital converter (ADC). Upper die Lower die



ZVW51 Control board





Package top Thre

Three dies stacked

This report is a detailed structure analysis of the lower die. It includes layer-bylayer analysis, cross section analysis of the main devices (logic, LDMOS, ESD device, precision resistor, etc.), and an estimation of the process flow for forming the trench structure. Some of the key features are:

- 1. Up to twenty cells are monitored
- 2. Silicon on Insulator (SOI) and Wafer Bonding process with <u>unique</u> trench isolation structure
- 3. BCDMOS (Bipolar, CMOS and LDMOS) process
- 4. Use of precision thin film resistor

Note:

The listed report price may not be accurate as it decreases over time. Please contact us for current report pricing <u>info@ltecusa.com</u>

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